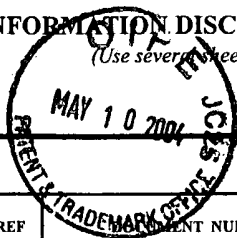


# INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)



Docket Number (Optional)

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Application Number

10/734,073

Applicant(s)

Degner et al.

Filing Date

Dec. 12, 2003

Group Art Unit

Unknown

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	A	4,386,979	5/31/83	Pierce et al.	204	298	
	B	See Below					
	C	4,564,435	1/14/86	Wickersham	204	298	
	D	4,931,135	6/5/90	Horiuchi et al.	156	643	
	E	4,820,371	4/11/89	A. D. Rose	156	345	
	F	4,904,621	2/27/90	Loewenstein	437	225	
	G	4,367,114	1/4/83	Steinberg et al.	156	643	
	H	4,297,162	10/27/81	Mundt et al.	156	643	
	I	4,963,713	10/16/90	Horiuchi et al.	219	121.45	1/18/99
	J	4,792,378	12/20/88	Rose et al.	156	643	
	K	4,544,091	10/1/85	Hidler et al.	228	124	

## FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO

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## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	B	McGuire, SEMICONDUCTOR MATERIAL AND PROCESS TECHNOLOGY HANDBOOK, FOR VERY LARGE SCALE INTEGRATION (VLSI) AND ULTRA LARGE SCALE INTEGRATION (ULSI), Copyright 1988, Noyes Publications, Chapter 5, Particularly Pages 272-279, Fig. 51a-iii

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.